

FIG. 1(A)

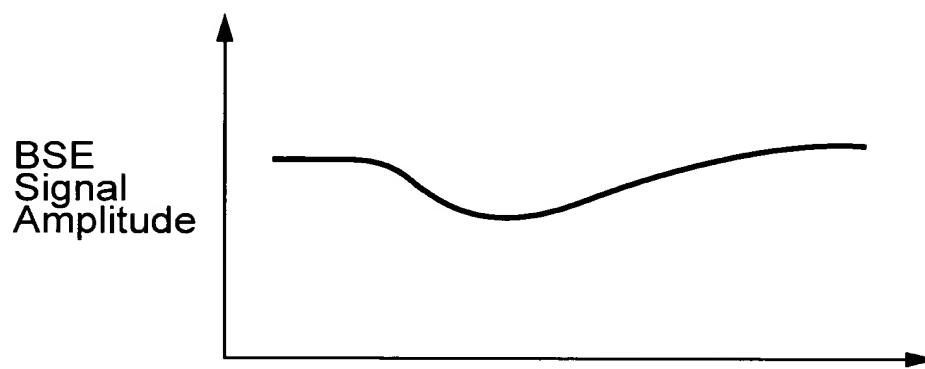


FIG. 1(B)

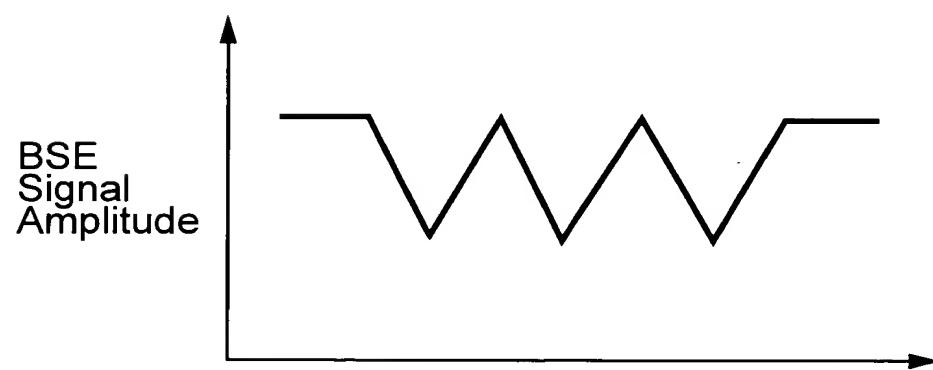


FIG. 1(C)

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Attorney Docket No.: 4641-55447-01;

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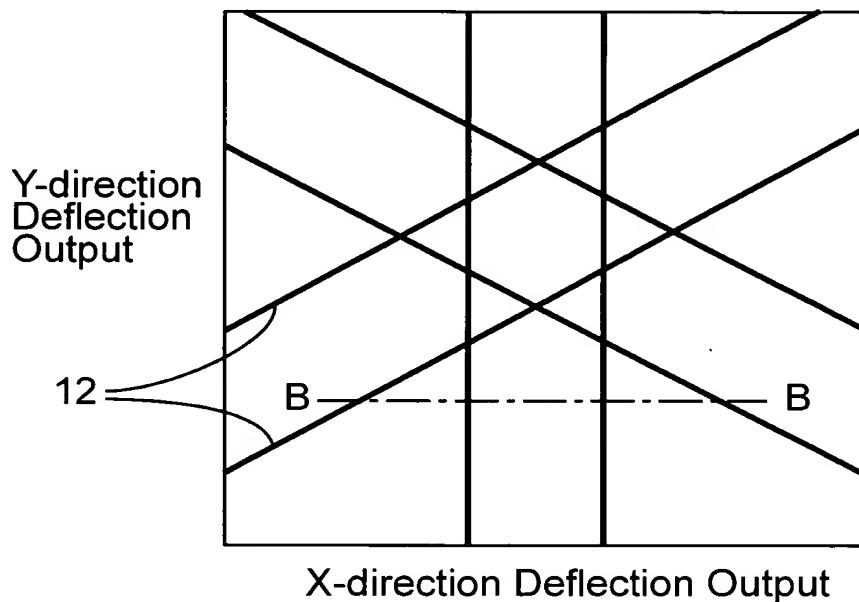


FIG. 2(A)

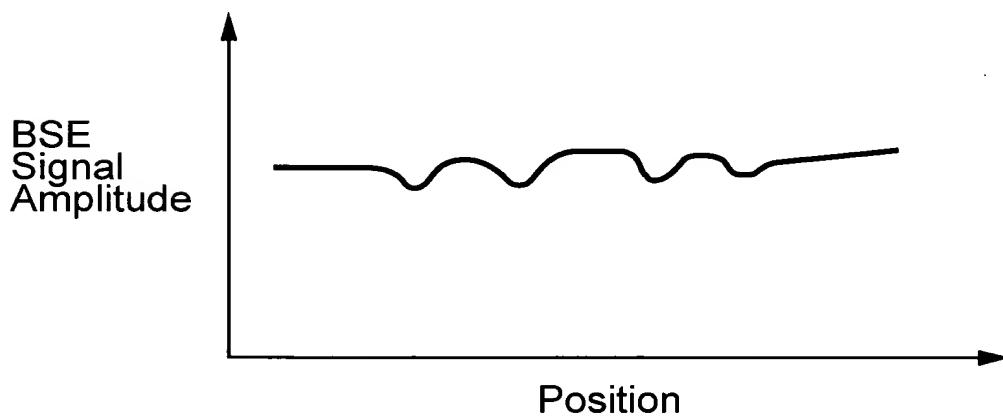


FIG. 2(B)

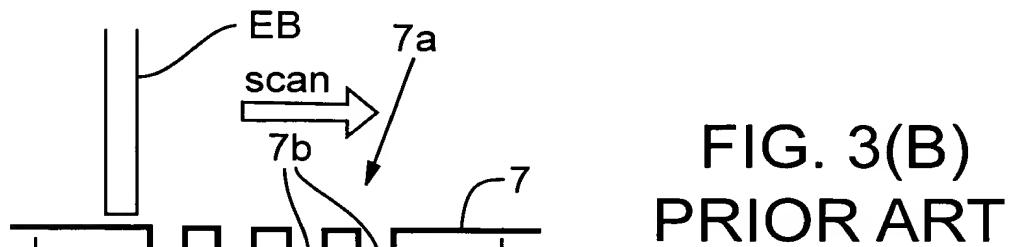
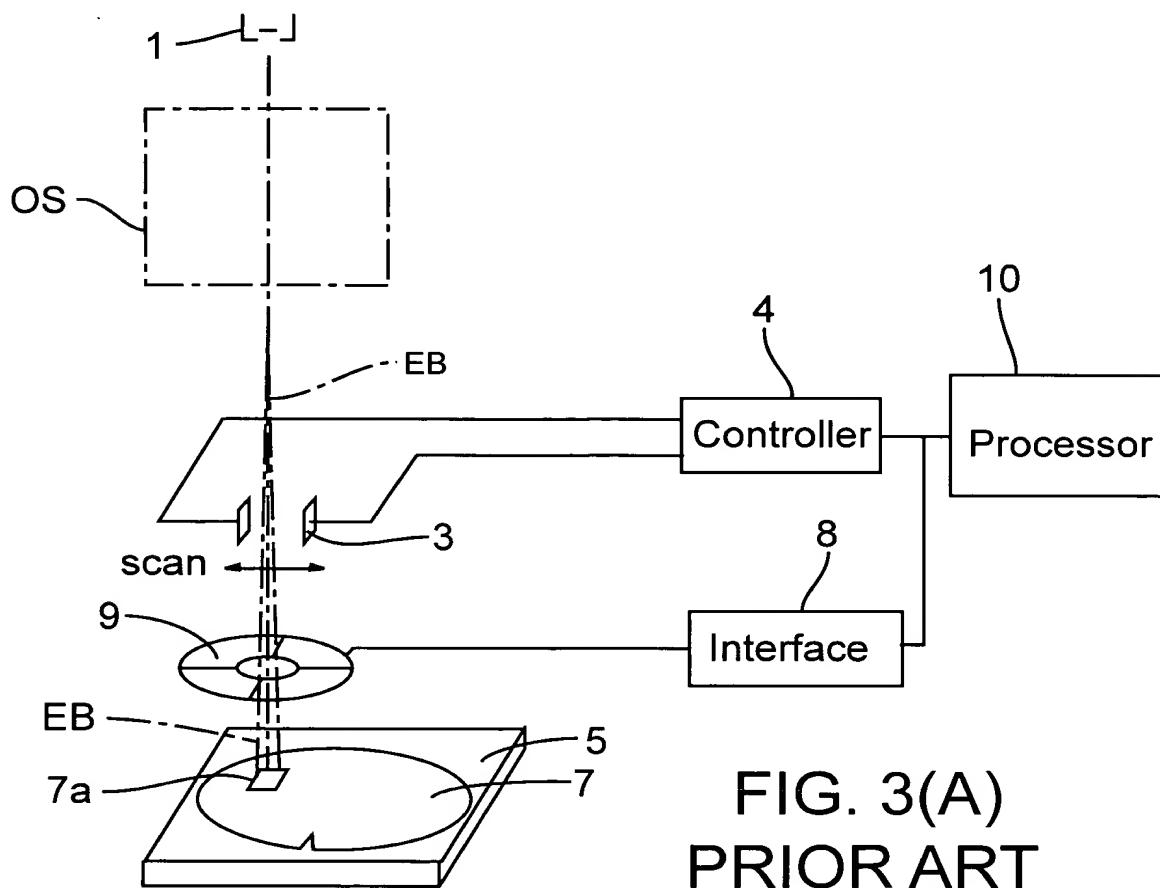


FIG. 3(C)
PRIOR ART

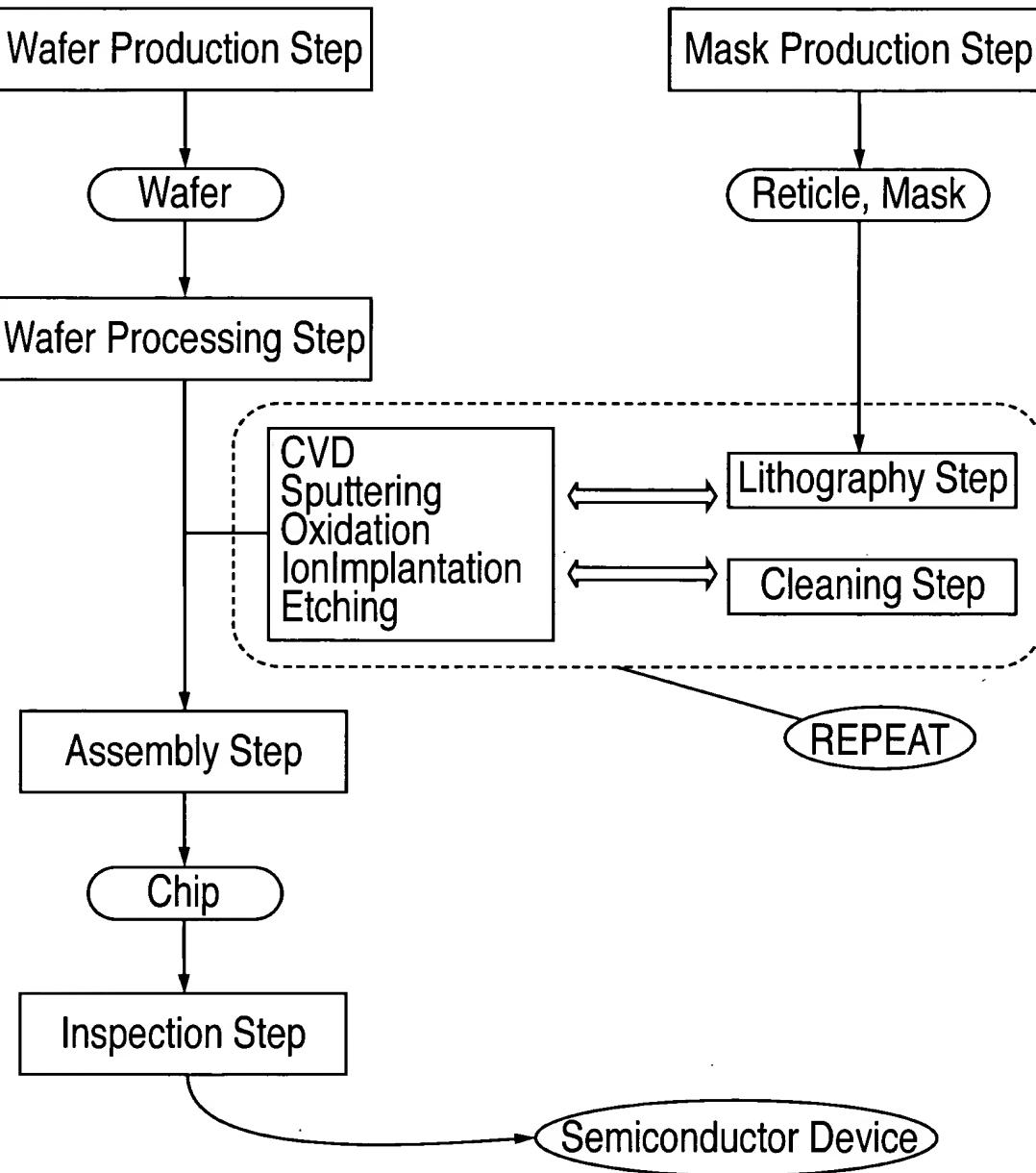
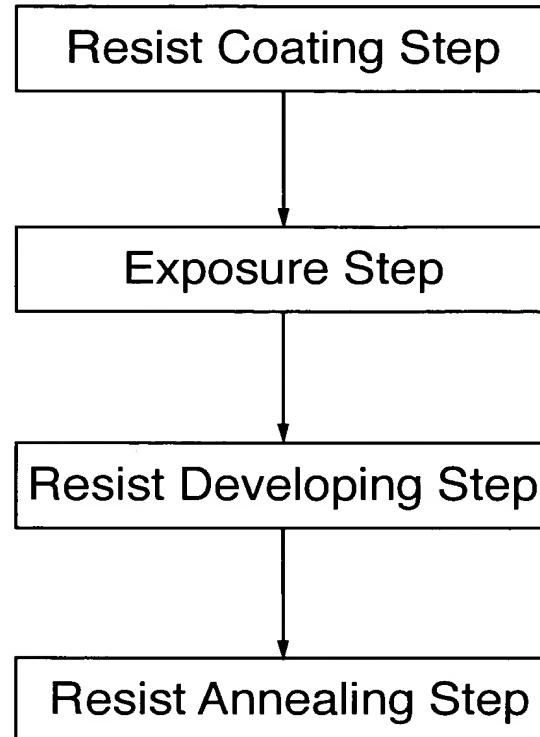


FIG. 4



Lithography Step

FIG. 5